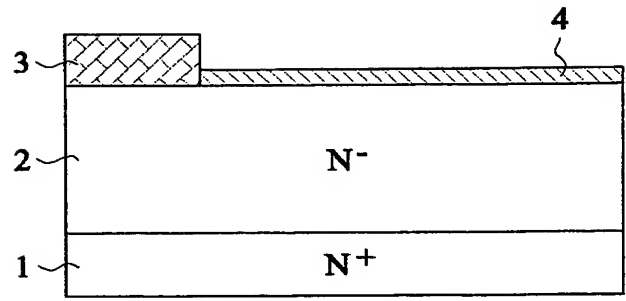
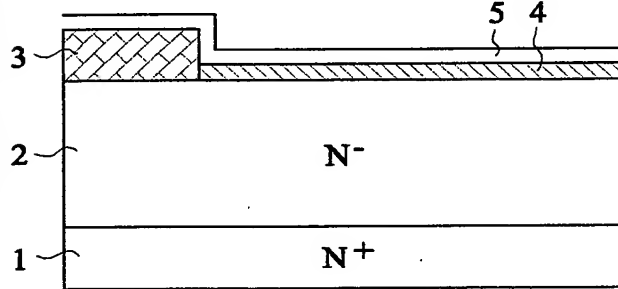


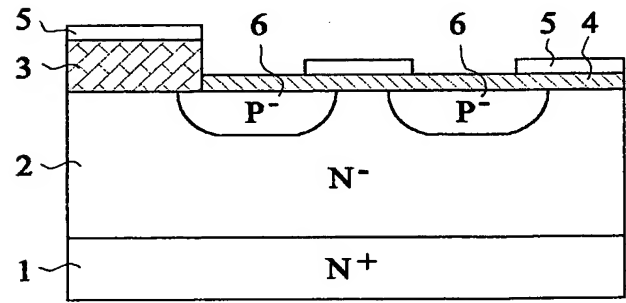
(a)



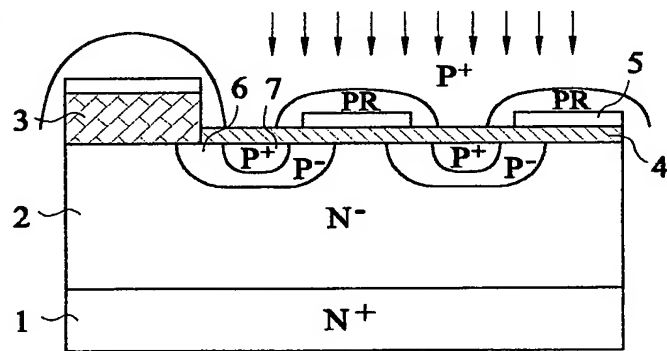
(b)



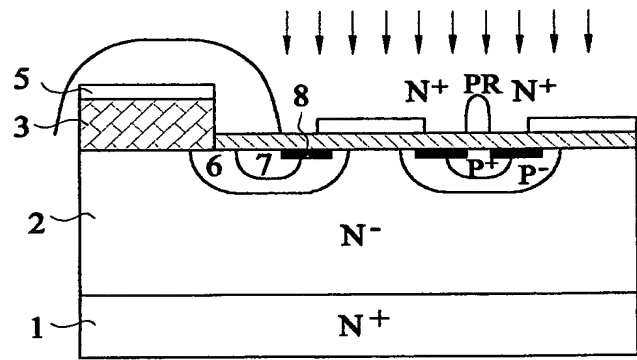
(c)



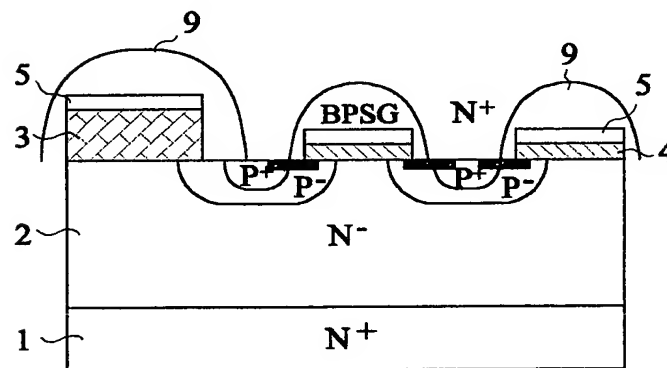
(d)



(e)

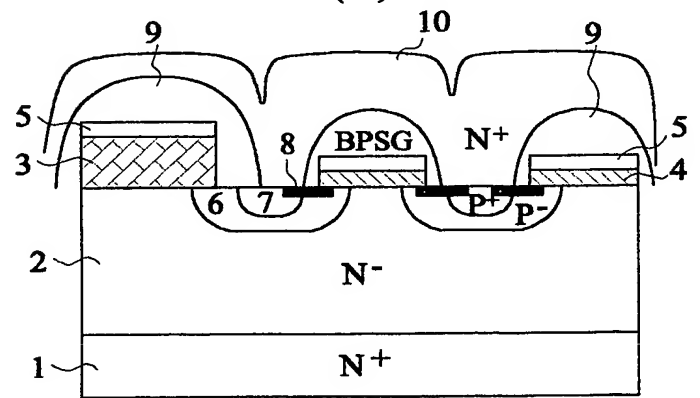


(f)



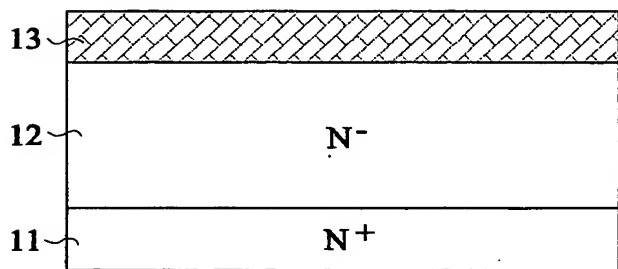
(g)

(PRIOR ART)

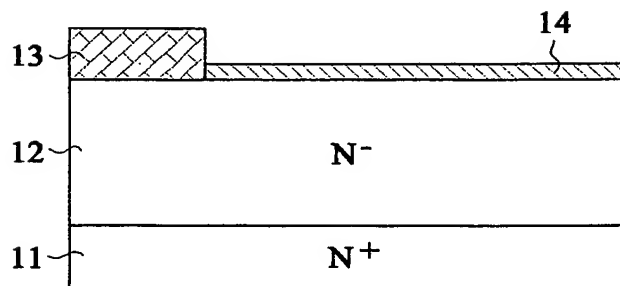


(h)

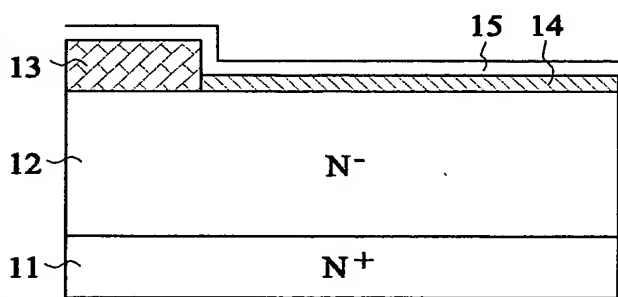
FIG. 1



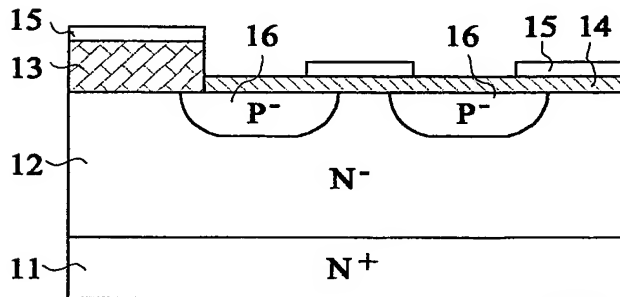
(a)



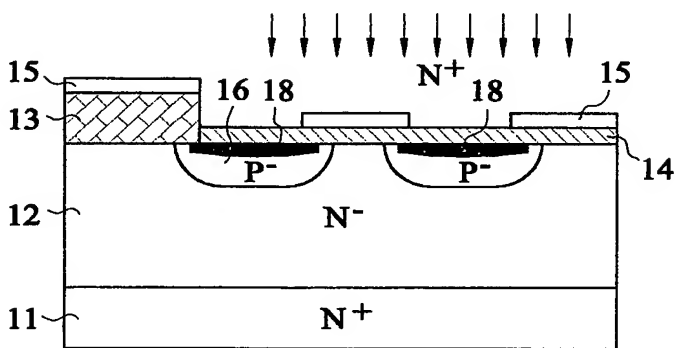
(b)



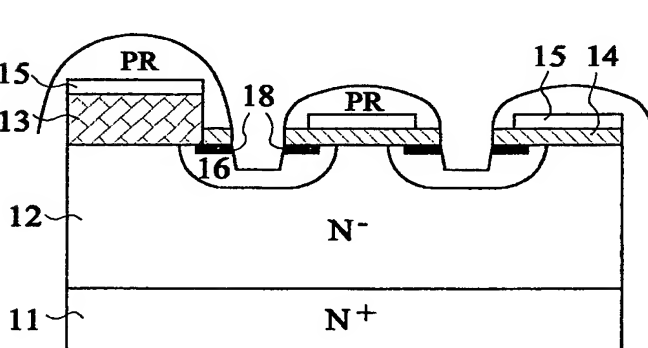
(c)



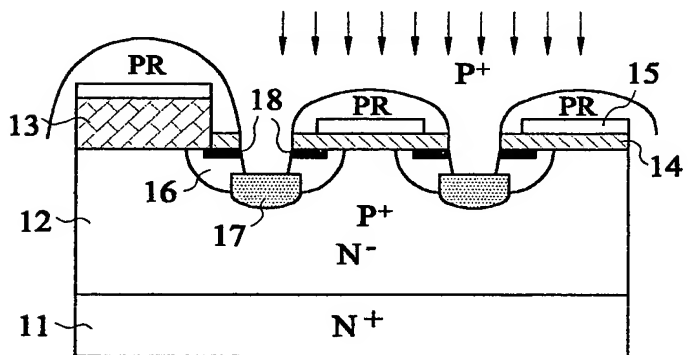
(d)



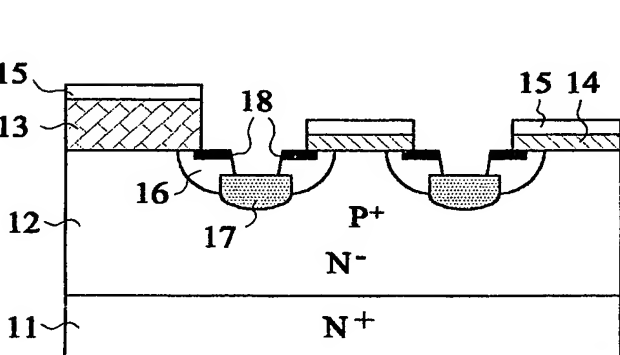
(e)



(f)

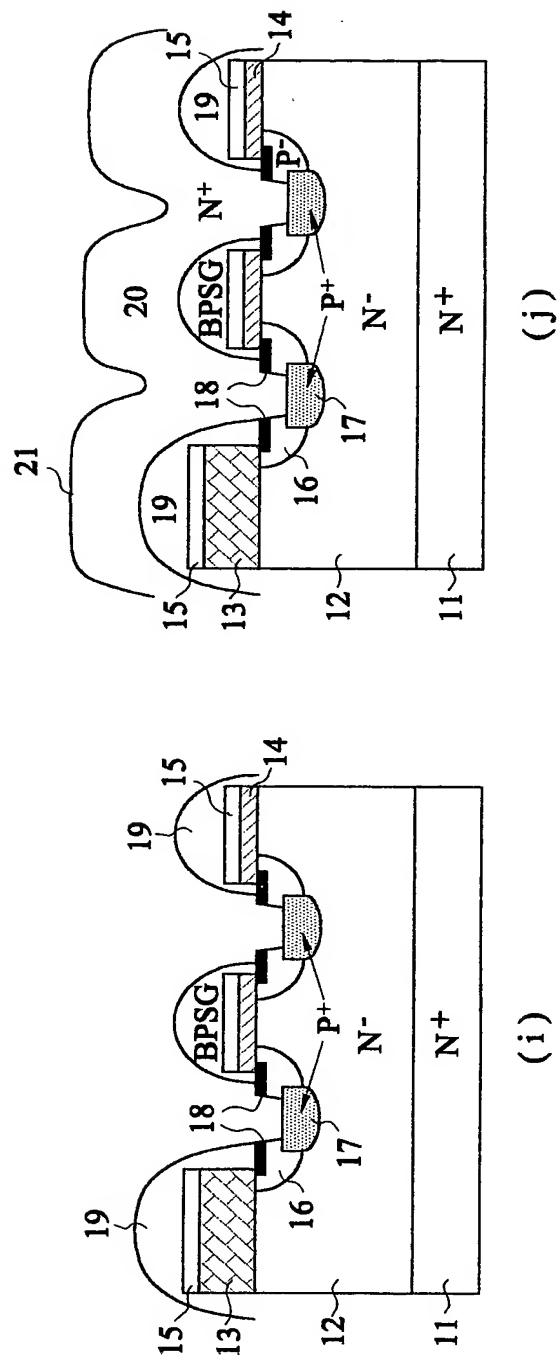


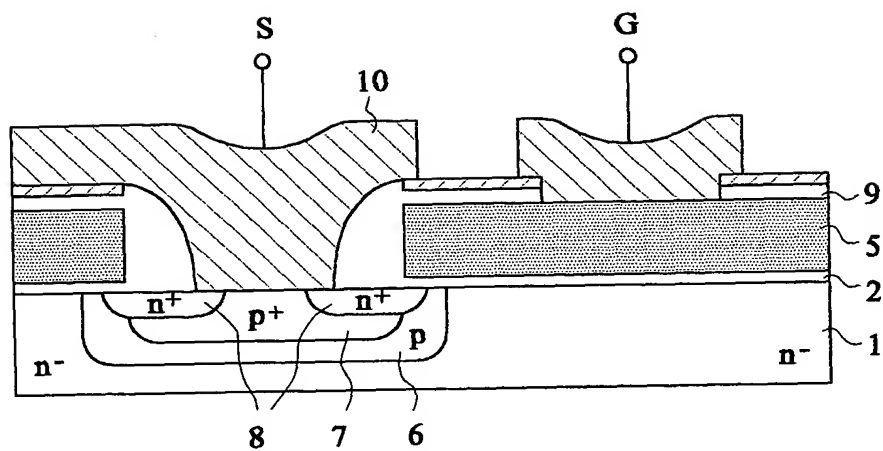
(g)



(h)

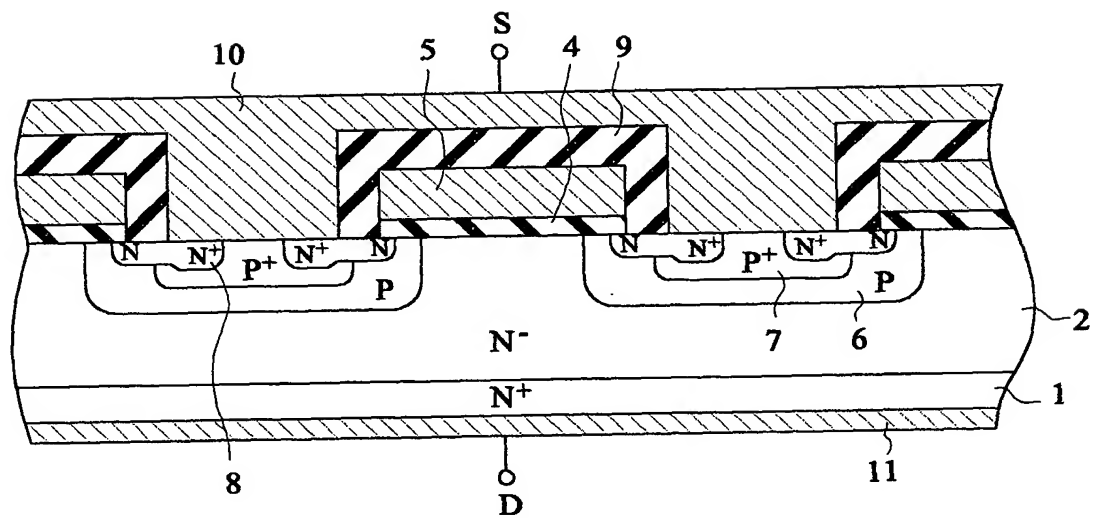
FIG. 2





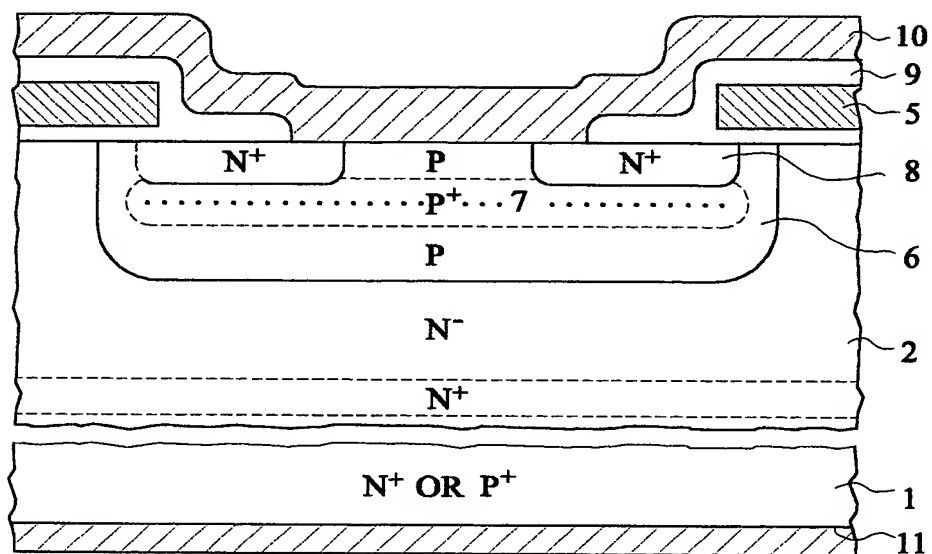
(PRIOR ART)

FIG. 3



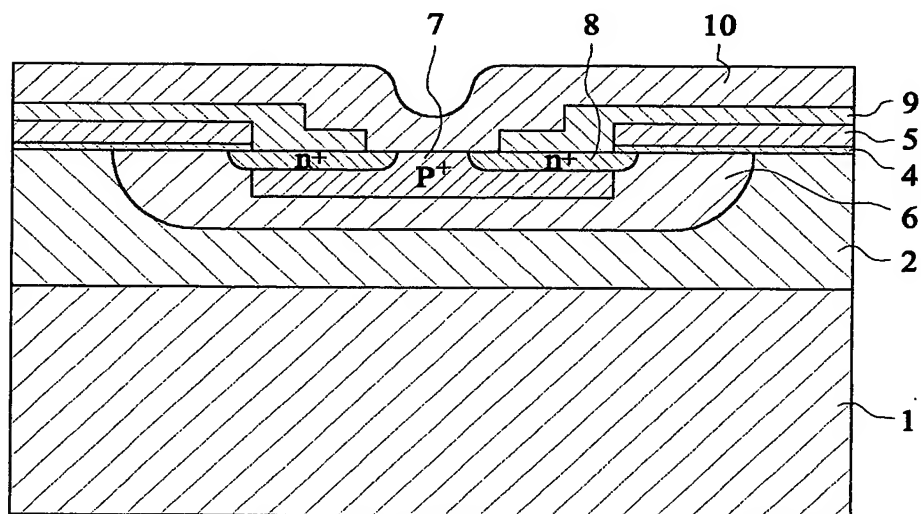
(PRIOR ART)

FIG. 4



(PRIOR ART)

FIG. 5



(PRIOR ART)

FIG. 6

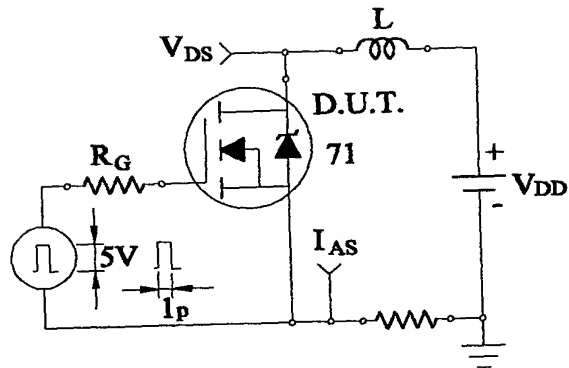


FIG. 7a

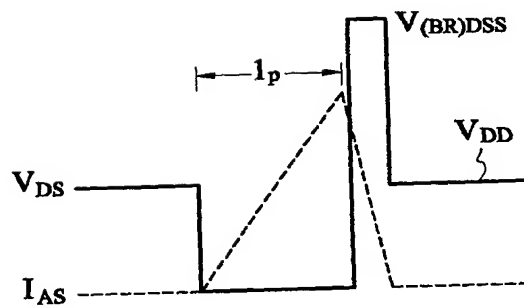


FIG. 7b

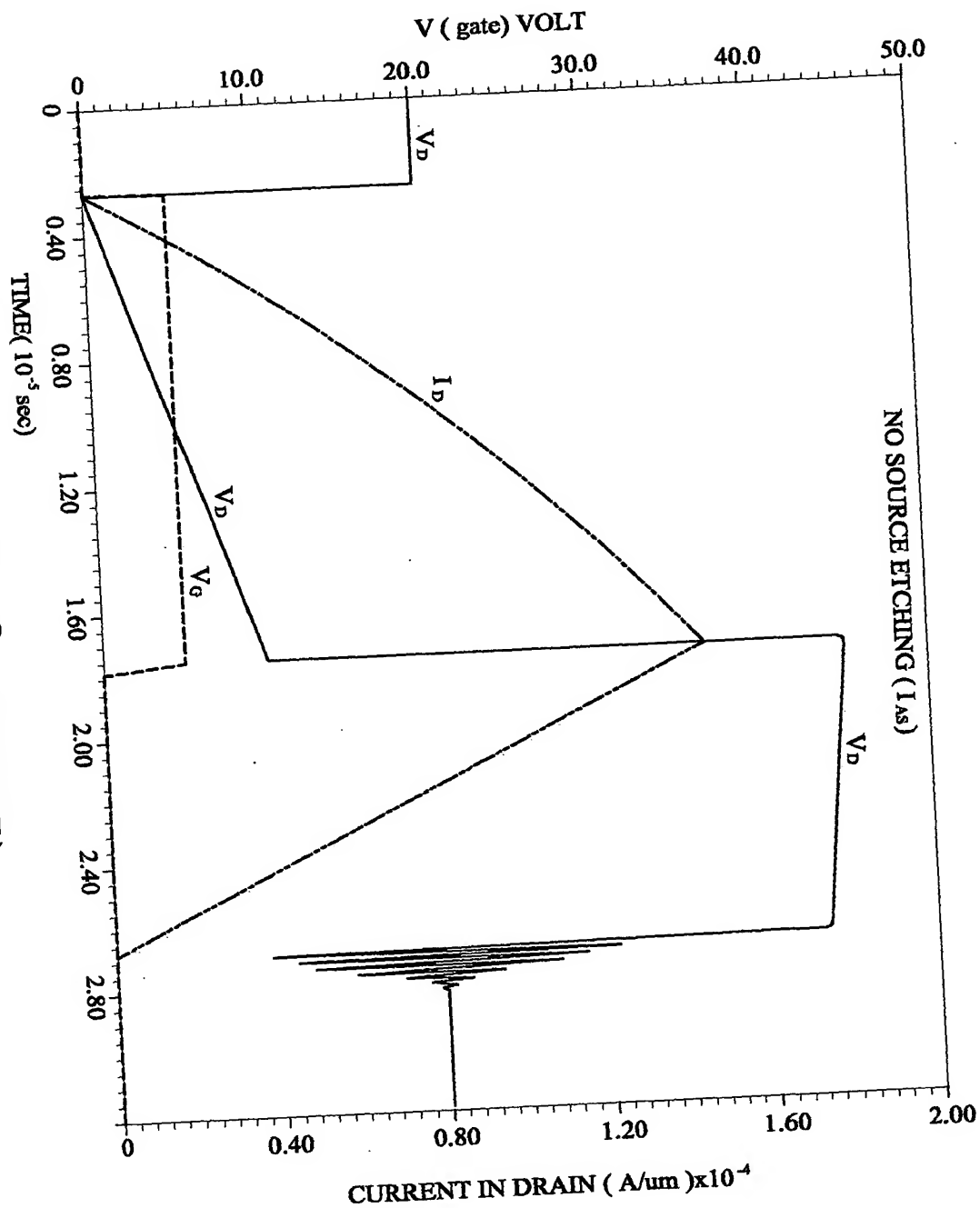


FIG. 8 (PRIOR ART)

FIG. 8 (PRIOR ART)

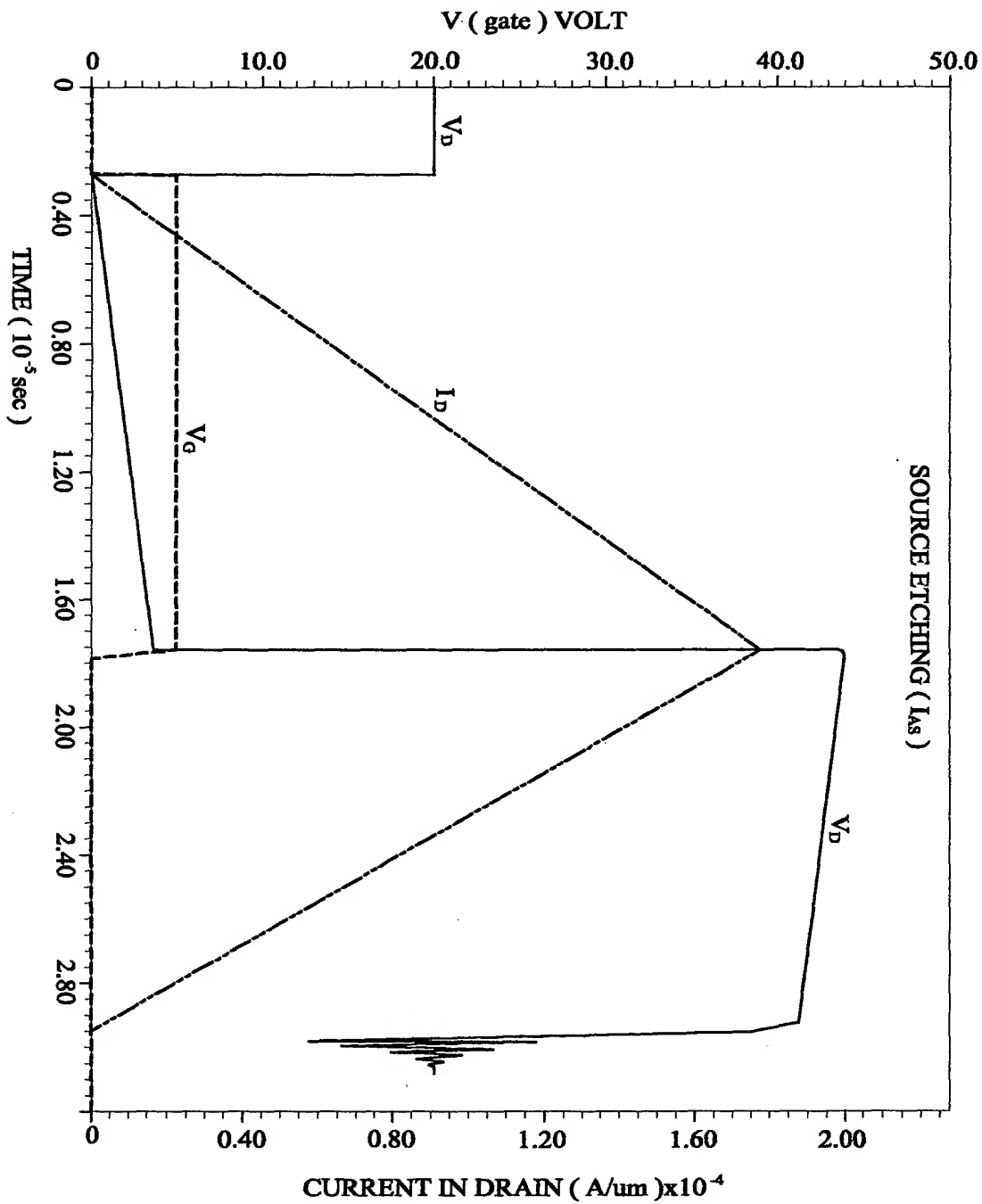


FIG. 9

Source etching (I_{AS})